

**Amendments to the Claims:**

The listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

1. (Currently Amended) A ~~process~~ method for forming an underlying film, comprising: irradiating the surface of an insulating film disposed on an electronic device substrate with plasma based on a process gas comprising at least an oxygen atom-containing gas, to thereby form an underlying film at the interface between the insulating film and the electronic device ~~substrate~~.  
substrate.

wherein the underlying film is an oxide film, and has a thickness of 6-12 Å.

2-5. (Canceled)

6. (Withdrawn) An electronic device material, comprising:  
an electronic device substrate,  
an underlying film disposed on the substrate, and

an insulating film disposed on the underlying film, wherein the underlying film is a film which has been formed by supplying plasma from the insulating layer side.

7. (Withdrawn) The electronic device material according to claim 6, wherein the insulating film is a film comprising a high-dielectric constant material.

8. (Currently Amended) A ~~process~~ method for forming an insulating film, comprising:

forming an insulating film on a substrate,

converting a process gas comprising at least an oxygen atom-containing gas on the insulating film to thereby generate oxygen radicals, and

irradiating the surface of the insulating film with the oxygen radicals so that the oxygen radicals penetrate the insulating film and react with the substrate to thereby form an oxide film at the interface between the insulating film and the ~~substrate~~. substrate.

wherein the oxide film has a thickness of 6-12 Å.

9-10. (Canceled).

11. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 8, wherein the process gas comprises at least one rare gas selected from the group consisting of Kr, Ar, He and Xe.

12. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 8, wherein the oxygen atom-containing gas is O<sub>2</sub> gas.

13. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 8, further comprising annealing the substrate after the formation of the oxide film.

14. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 13, wherein the annealing is conducted in an atmosphere of N<sub>2</sub>, O<sub>2</sub>, or N<sub>2</sub> and O<sub>2</sub>.

15. (Currently Amended) A ~~process~~ method forming an insulating film according to claim 13, wherein the annealing is conducted at a temperature of 500-1100°C.

16. (Currently Amended) A ~~process~~ method for forming an insulating film, comprising:

forming a high-dielectric constant insulating film on a substrate,  
generating plasma based on a process gas comprising at least an oxygen  
atom-containing gas on the high-dielectric constant insulating film, and  
irradiating the surface of the high-dielectric constant insulating film with  
the plasma to thereby form an oxide film at the interface between the high-  
dielectric constant insulating film and the ~~substrate~~. substrate,  
wherein the oxide film has a thickness of 6-12 Å.

17. (Currently Amended) A ~~process~~ method for forming an insulating  
film according to claim 16, wherein the plasma is generated based on microwave  
via a plane antenna member (RLSA) having a plurality of slots.

18. (Currently Amended) A ~~process~~ method for forming an insulating  
film according to claim 16, wherein the high-dielectric constant insulating film  
comprises at least one material selected from the group consisting of  $\text{Al}_2\text{O}_3$ ,  $\text{ZrO}_2$ ,  
 $\text{HfO}_2$ ,  $\text{Ta}_2\text{O}_5$ ,  $\text{ZrSiO}$ ,  $\text{HfSiO}$  and  $\text{ZrAlO}$ .

19. (Currently Amended) A ~~process~~ method for forming an insulating  
film according to claim 16, wherein the process gas comprises at least one rare  
gas selected from the group consisting of Kr, Ar, He and Xe.

20. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 16, wherein the oxygen atom-containing gas is O<sub>2</sub> gas.

21. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 16, further comprising annealing the substrate after the formation of the oxide film.

22. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 21, wherein the annealing is conducted in an atmosphere of N<sub>2</sub>, O<sub>2</sub>, or N<sub>2</sub> and O<sub>2</sub>.

23. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 21, wherein the annealing is conducted at a temperature of 500-1100°C.

24-27. (Canceled).

28. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 16, further comprising plasma nitriding the surface of the substrate before the formation of the high-dielectric constant insulating film.

29. (Currently Amended) A ~~process~~ method for forming an insulating film, comprising:

forming a HfSiO film on a substrate,

generating plasma based on a process gas comprising at least an oxygen atom-containing gas on the HfSiO film, and

irradiating the surface of the HfSiO film with the plasma, to thereby form an oxide film at the interface between the HfSiO film and the ~~substrate~~.  
substrate,

wherein the oxide film has a thickness of 6-12 Å.

30. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 29, wherein the plasma is generated based on microwave via a plane antenna member (RLSA) having a plurality of slots.

31. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 29, wherein the oxygen atom-containing gas is O<sub>2</sub> gas and the process gas comprises at least one rare gas selected from the group consisting of Kr, Ar, He and Xe.

32. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 29, further comprising annealing the substrate after formation of the oxide film.

33. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 32, wherein the annealing is conducted in an atmosphere of N<sub>2</sub>, O<sub>2</sub>, or N<sub>2</sub> and O<sub>2</sub>.

34. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 32, wherein the annealing is conducted at a temperature of 600-1100°C.

35. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 29, wherein the substrate is at a temperature from room temperature to 500°C.

36. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 29, wherein the oxide film is formed at a pressure of 3-500 Pa.

37-38. (Canceled).

39. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 29, further comprising plasma nitriding the surface of the substrate before the formation of the HfSiO film.

40. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 29, wherein the HfSiO film is formed by using tertiary ethoxy hafnium (HTB:  $\text{Hf}(\text{OC}_2\text{H}_5)_4$ ) and silane gas ( $\text{SiH}_4$ ).

41. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 29, further comprising washing the substrate before the formation of the HfSiO film.

42. (Currently Amended) A ~~process~~ method for forming an insulating film, comprising:

forming a HfSiO film on a substrate,

generating plasma based on a process gas comprising at least an oxygen atom-containing gas on the HfSiO film,

irradiating the surface of the HfSiO film with the plasma to thereby form an oxide film at the interface between the HfSiO film and the substrate, and

nitriding the surface of the HfSiO ~~film~~ film,

wherein the oxide film has a thickness of 6-12 Å.



43. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 42, further comprising plasma nitriding the surface of the substrate before the formation of the HfSiO film.

44. (Currently Amended) A ~~process~~ method for forming an insulating film according to claim 42, further comprising washing the substrate before the formation of the HfSiO film.

45. (Withdrawn) A semiconductor manufacturing apparatus for forming an insulating film, said apparatus comprising:

- a cassette station for disposing a substrate,
- a first arm for putting in and out with respect to the cassette,
- at least one plasma processing unit for plasma oxidizing or plasma nitriding the substrate, a heating unit for heating the substrate,
- a heating reaction furnace for forming a high-dielectric constant film on the substrate,
- a transportation chamber for disposing the plasma processing unit and the heating unit,
- a second arm disposed in the transportation chamber, for transporting the substrate between the respective units, and

a load lock for conducting the communication/cutoff between the respective processing units.

46. (Currently Amended) A process method for forming an electronic device, comprising:

forming a high-dielectric constant gate insulating film on a substrate,  
generating plasma based on a process gas comprising at least an oxygen atom-containing gas on the high-dielectric constant gate insulating film,

irradiating the surface of the high-dielectric constant gate insulating film with the plasma, to thereby form an oxide film at the interface between the high-dielectric constant gate insulating film and the substrate, and

forming a gate electrode on the high-dielectric constant gate insulating ~~film~~ film,

wherein the oxide film has a thickness of 6-12 Å.

47. (Currently Amended) A process method for forming an electronic device according to claim 46, wherein the plasma is generated based on microwave via a plane antenna member.

48-49. (Canceled).

50. (Currently Amended) A ~~process~~ method for forming an electronic device according to claim 46, further comprising nitriding the surface of the high-dielectric constant gate insulating film after the formation of the oxide film.

51. (Currently Amended) A ~~process~~ method for forming an electronic device according to claim 46, further comprising annealing the surface of the high-dielectric constant gate insulating film after the formation of the oxide film.

52. (Canceled).

53. (Currently Amended) A ~~process~~ method for forming an electronic device according to claim 46, wherein the high-dielectric constant gate insulating film comprises at least one material selected from the group consisting of  $\text{Al}_2\text{O}_3$ ,  $\text{ZrO}_2$ ,  $\text{HfO}_2$ ,  $\text{Ta}_2\text{O}_5$ ,  $\text{ZrSiO}$ ,  $\text{HfSiO}$  and  $\text{ZrAlO}$ .

54. (Currently Amended) A ~~process~~ method for forming an electronic device according to claim 46, further comprising plasma nitriding the surface of the substrate before the formation of the high-dielectric constant gate insulating film.

55. (New) A method for forming an insulating film according to claim 16, further comprising nitriding the surface of the high-dielectric constant gate insulating film after the formation of the oxide film.